



PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of)	
Julia S. SVIRCHEVSKI et al.)	Group Art Unit: 1765
Application No. 09/336,401)	Examiner: L. Umez-Eronini
Filed: June 18, 1999 (CPA filed 11/27/2001))	Attorney Docket No. LAM1P109
For: POST-PLASMA PROCESSING WAFER)	Date: May 20, 2002
CLEANING METHOD AND SYSTEM)	

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231 on May 20, 2002.

Signed: _____

Diane Schwanbeck

AMENDMENT

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Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

Applicants submit this paper in response to the Office Action dated December 19, 2001. A response to this Office Action was due on March 19, 2002. Accordingly, Applicants are concurrently submitting a request for a two-month extension of the period for response. Please amend this application as follows:

IN THE CLAIMS:

Please amend claim 6 as indicated below. Attached hereto as a separate page is a "marked-up" version of claim 6 that show the changes made to this claim. For the Examiner's convenience, all pending claims are reproduced below, with the claim that has been amended herein being indicated as such.

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